	Туре	Hits	Search Text	DBs	Time Stamp	Comments	Error Definition	Errors
-	BRS	73461	dram	USPAT; US-PGPUB; EPO; 2003/06/12 JPO; DERWENT; 09:14 IBM_TDB	2003/06/12 09:14			0
2	BRS	16681	dram and (bit adj line)	USPAT; US-PGPUB; EPO; 2003/06/11 JPO; DERWENT; 13:38 IBM_TDB	2003/06/11 13:38			0
က	BRS	11541	dram and ((bit adj line) and (word adj line))	USPAT; US-PGPUB; EPO; 2003/06/11 JPO; DERWENT; 13:45 IBM_TDB	2003/06/11 13:45			0
4	BRS	0	dram and (architetecture)	B; EPO; :WENT;	2003/06/11 13:46			0
ري 	BRS	1051	(dram and ((bit adj line) and (word adj line))) and (LSI)	USPAT; US-PGPUB; EPO; 2003/06/11 JPO; DERWENT; 13:47 IBM_TDB	2003/06/11 13:47			0
9	BRS	133	((dram and ((bit adj line) and (word adj line))) and (LSI)) and (self adj alignment)	USPAT; US-PGPUB; EPO; 2003/06/11 JPO; DERWENT; 15:35 IBM_TDB	2003/06/11 15:35			0
	BRS	44	(((dram and ((bit adj line) and (word USPAT; adj line))) and (LSI)) and (self adj US-PGF alignment)) and (stacked adj JPO; DE capacitor)	oUB; EPO; ERWENT; IB	2003/06/12 " 09:20			0
ω	IS&R	2	("5776815").PN.	USPAT; US-PGPUB; EPO; 2003/06/12 JPO; DERWENT; 09:38 IBM_TDB	2003/06/12 09:38			0

	Туре	Type Hits	Search Text	ÓBS	Time Stamp Comments	Comments	Error Definition	Errors
6	IS&R 12	12	(("5206183") or ("5338700") or ("5488011") or ("5498562") or ("5500384") or ("5580011")).PN.	USPAT; US-PGPUB; EPO; 2003/06/12 JPO; DERWENT; 09:42 IBM_TDB	2003/06/12 09:42			0
10	10 IS&R 12	12	(("5206183") or ("5338700") or ("5488011") or ("5498562") or ("5500384") or ("5580811")).PN.	USPAT; US-PGPUB; EPO; 2003/06/12 JPO; DERWENT; 09:51 IBM_TDB	2003/06/12 09:51			0
-	11 IS&R 2	2	("5654236").PN.	USPAT; US-PGPUB; EPO; 2003/06/12 JPO; DERWENT; 10:19 IBM TDB	2003/06/12 10:19			0

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L115 ANSWER 1 OF 2 WPIX
                            (C) 2003 THOMSON DERWENT
                        WPIX
AN .
    2002-530889 [57]
DNN N2002-420368
                        DNC C2002-150515
    Method for the integration of DRAM memory by providing a cell architecture
     that augments the density of integration.
DC
    L03 U11 U14
     CORONEL, P; LEVERD, F; PIAZZA, M
IN
    (SGSA) STMICROELECTRONICS SA
PA
CYC 2
                                                       H01L021-8242
                   A1 20020719 (200257)*
                                               24p
    FR 2819633
     US 2002110976 A1 20020815 (200260)
                                                       H01L021-8242
    FR 2819633 A1 FR 2001-691 20010118; US 2002110976 A1 US
     2002-42520 20020108
PRAI FR 2001-691
                      20010118
    ICM H01L021-8242
IC
     ICS H01L021-20; H01L021-4763
          2819633 A UPAB: 20020906
ΔR
     NOVELTY - A method for the integration of a Dynamic Random Access Memory
     (DRAM), allowing a freedom from the alignment margins inherent in the
     photoengraving of the upper electrode for the contact passage of the bit
     line, the retreat of the upper electrode being auto-aligned on the lower
     electrode, consists of:
          (a) forming a topographical difference at the spot (A) where the
     opening for the upper electrode is to be realised;
          (b) depositing a layer of non-doped polysilicon on the upper
     electrode;
          (c) producing an implantation of strongly inclined doping in this
     (d) selectively engraving the non-doped part of the layer situated in the lower part of the zone (A) presenting the topographical difference;
          (e) and engraving the remaining part of the polysilicon layer as well
     as the upper electrode layer situated in the lower part.
          USE - The method is used for constructing an improved DRAM cell
     architecture to augment the density of integration.
          ADVANTAGE - The method provides a cell architecture which improves
     the density of integration whilst retaining the same capacity produced by
     conventional methods whilst overcoming their lack of process robustness
     and limitations of productivity and cycle time.
          DESCRIPTION OF DRAWING(S) - The drawing illustrates the DRAM cell
     architecture according to the invention.
          Lower electrode layer; elec1
          Upper electrode layer; elec2
          Silicon oxide layers. TEOS
     Dwg.9/9
     CPI EPI
FS
FA
     AB; GI
     CPI: L03-G04A; L04-C11C
MC
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EPI: U11-C18B5; U14-C01